



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Yoshimasa KAWASE

Title: WAFER HEAT-TREATMENT SYSTEM AND WAFER HEAT-TREATMENT METHOD

Appl. No.: 10/066,783

Filing Date: 02/06/2002

Examiner: Unassigned

Art Unit: 3749

PETITION FOR EXTENSION OF TIME

Commissioner for Patents
Washington, D.C. 20231

Sir:

Applicant hereby petitions the Commissioner under 37 C.F.R. §1.136(a) for a two-month extension of time for response in the above-identified application for the period required to make the attached response timely.

The extension fee for response within the second month is \$400.00. A check including this amount is enclosed herewith.

The Commissioner is hereby authorized to charge any additional fees which may be required regarding this application under 37 C.F.R. §§ 1.16-1.17, or credit any overpayment, to Deposit Account No. 19-0741. Should no proper payment be enclosed herewith, as by a check being in the wrong amount, unsigned, post-dated, otherwise improper or informal or even entirely missing, the Commissioner is authorized to charge the unpaid amount to Deposit Account No. 19-0741.

Respectfully submitted,

Date: June 20, 2002

By

FOLEY & LARDNER
Customer Number: 22428



22428

PATENT TRADEMARK OFFICE

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